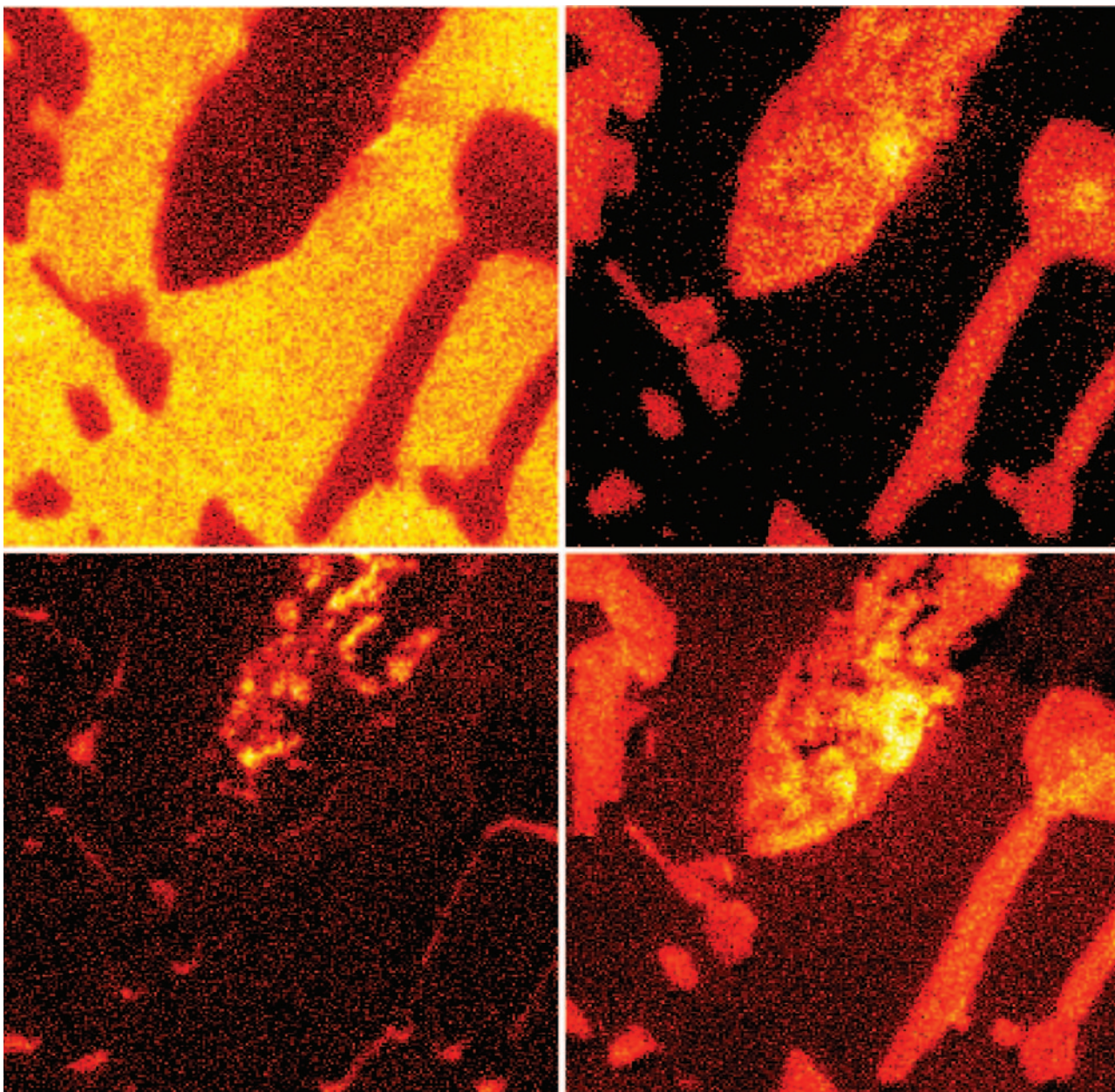


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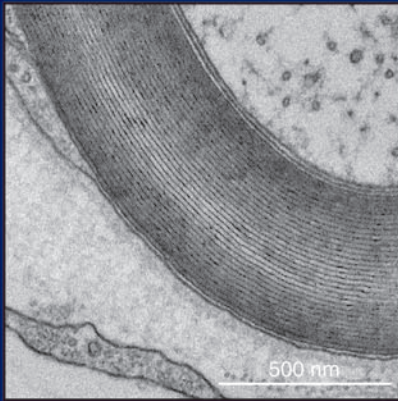
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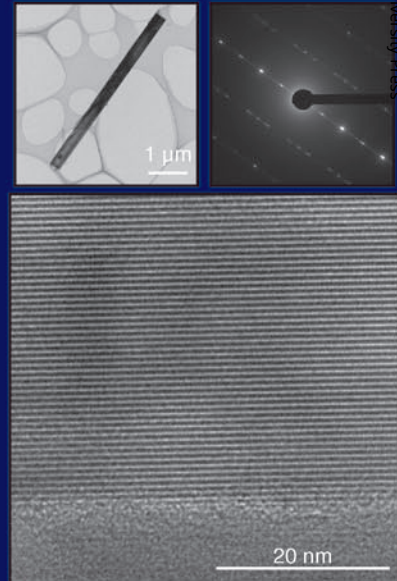
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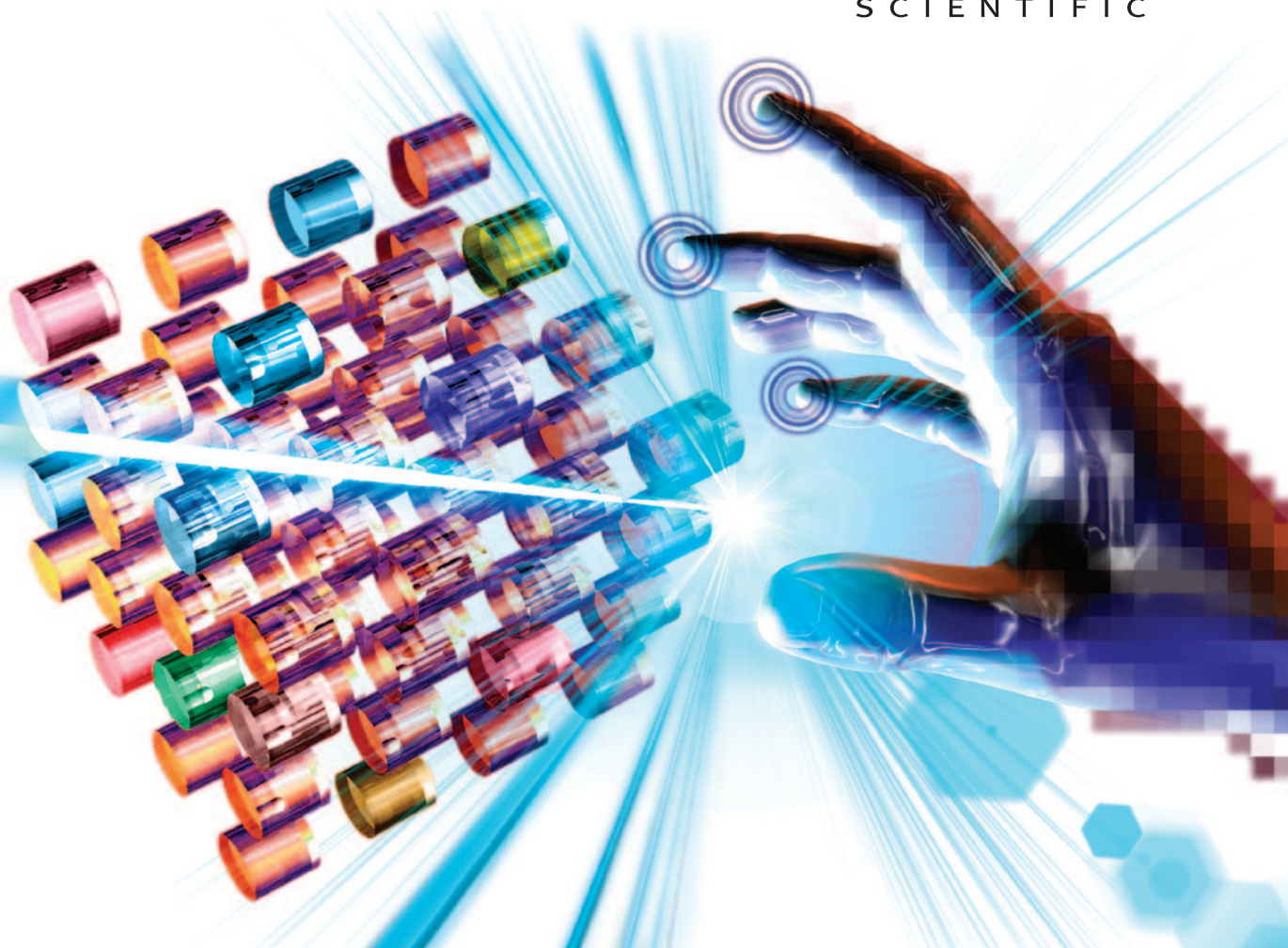
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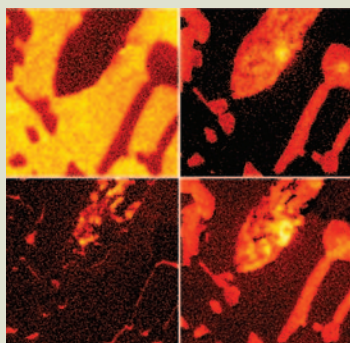
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About the Cover



Auger maps of a steel alloy surface. Clockwise from top left: Fe image, Mn image, B image, C image. Image width = 1.8 μm .

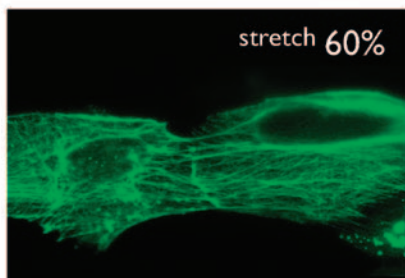
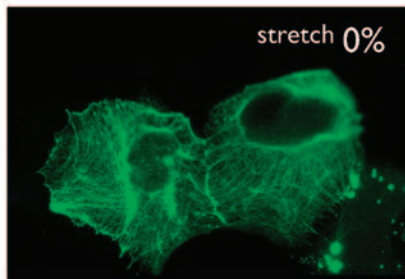
See article by Raman et al.

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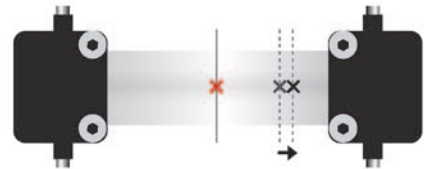
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